

Problems With Parallel-Plate C Drive

- Nonlinear voltage-to-force transfer function
 - ↳ Resonance frequency becomes dependent on parameters (e.g., bias voltage V_p)
 - ↳ Output current will also take on nonlinear characteristics as amplitude grows (i.e., as x approaches d_0)
 - ↳ Noise can alias due to nonlinearity
- Range of motion is small
 - ↳ For larger motion, need larger gap ... but larger gap weakens the electrostatic force
 - ↳ Large motion is often needed (e.g., by gyroscopes, vibromotors, optical MEMS)

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Electrostatic Comb Drive

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Electrostatic Comb Drive

- Use of comb-capacitive transducers brings many benefits
 - ↳ Linearizes voltage-generated input forces
 - ↳ (Ideally) eliminates dependence of frequency on dc-bias
 - ↳ Allows a large range of motion

Comb-Driven Folded Beam Actuator

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Comb-Drive Force Equation (1st Pass)

$$C(x) = \frac{2\epsilon_0 x h}{d} \rightarrow \left[\frac{\partial C}{\partial x} = \frac{2\epsilon_0 h}{d} \right]$$

$$F_d = \frac{\partial W}{\partial x} = \frac{1}{2} \frac{\partial C}{\partial x} (V_p - V_i)^2 = \frac{2}{2} \frac{\epsilon_0 h}{d} (V_p^2 - 2V_p V_i + V_i^2) \approx -2V_p \frac{\epsilon_0 h}{d} V_i = F_{d1}$$

When $V_i = (+) \rightarrow F_{d1} (-)$ ✓

↳ But wait: This ignores other practical effects! (No dependence on x ! LINEAR!)

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Lateral Comb-Drive Electrical Stiffness

Top View

Side View

- Again: $C(x) = \frac{2N\epsilon h x}{d} \rightarrow \frac{\partial C}{\partial x} = \frac{2N\epsilon h}{d}$
- No $(\partial C/\partial x)$ x-dependence \rightarrow no electrical stiffness: $k_e = 0!$
- Frequency immune to changes in V_P or gap spacing!

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Typical Drive & Sense Configuration

2-port Lateral Microresonator

Simple Analysis:

$$F_{d1} = \frac{1}{2} \frac{\partial C_1}{\partial x} (V_1 - V_{P1})^2 = \frac{1}{2} \left(-\frac{\epsilon_0 h}{d} \right) (N_1^2 - 2V_{P1}N_1 + V_{P1}^2) (2N_f)$$

$$F_{d2} = \frac{1}{2} \frac{\partial C_2}{\partial x} (V_2 - V_{P2})^2 = \frac{1}{2} \left(\frac{\epsilon_0 h}{d} \right) (N_2^2 - 2V_{P2}N_2 + V_{P2}^2) (2N_f)$$

$$\therefore F_{net} = F_{d1} + F_{d2} = \frac{1}{2} \left(\frac{\epsilon_0 h}{d} \right) (N_2^2 - N_1^2 - 2(V_{P2}N_2 - V_{P1}N_1) + V_{P2}^2 - V_{P1}^2) (2N_f)$$

For $V_1 = V_2, V_i = -N_2$

$$F_{net} = 2(2N_f) \left(\frac{\epsilon_0 h}{d} \right) V_{P1} N_1$$

Electrically Connected

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Comb-Drive Force Equation (2nd Pass)

- In our 1st pass, we accounted for
 - ↳ Parallel-plate capacitance between stator and rotor
- ... but neglected:
 - ↳ Fringing fields
 - ↳ Capacitance to the substrate
- All of these capacitors must be included when evaluating the energy expression!

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Comb-Drive Force With Ground Plane Correction

- Finger displacement changes not only the capacitance between stator and rotor, but also between these structures and the ground plane \rightarrow modifies the capacitive energy

$$F_{e,x} = \frac{\partial W'}{\partial x} = \frac{1}{2} \frac{dC_{sw}}{dx} V_s^2 + \frac{1}{2} \frac{dC_{rp}}{dx} V_r^2 + \frac{1}{2} \frac{dC_{rs}}{dx} (V_s - V_r)^2$$

[Gary Fedder, Ph.D., UC Berkeley, 1994]

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UC Berkeley Capacitance Expressions

- Case: $V_r = V_p = 0V$
- C_{sp} depends on whether or not fingers are engaged

$$C_{sp} = N[C'_{sp,e}x + C'_{sp,u}(L-x)]$$

$$C_{rs} = NC'_{rs}x$$

Capacitance per unit length

Region 2 Region 3

[Gary Fedder, Ph.D., UC Berkeley, 1994]

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$$F_{e,x} = \frac{N}{2} (C'_{rs} + C'_{sp,e} - C'_{sp,u}) V_s^2$$

(for $V_r = V_p = 0$)

[Gary Fedder, Ph.D., UC Berkeley, 1994]

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UC Berkeley Simulate to Get Capacitors → Force

- Below: 2D finite element simulation

$$F_{e,x} = \frac{N}{2} (C'_{rs} + C'_{sp,e} - C'_{sp,u}) V_s^2$$

20-40% reduction of $F_{e,x}$

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UC Berkeley Vertical Force (Levitation)

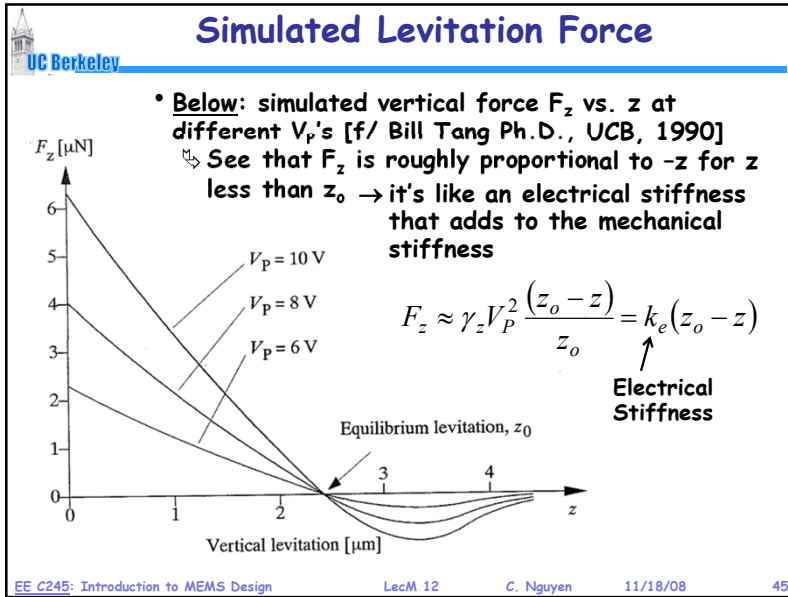
$$F_{e,z} = \frac{\partial W'}{\partial z} = \frac{1}{2} \frac{dC_{sp}}{dz} V_s^2 + \frac{1}{2} \frac{dC_{rp}}{dz} V_r^2 + \frac{1}{2} \frac{dC_{rs}}{dz} (V_s - V_r)^2$$

- For $V_r = 0V$ (as shown): $F_{e,z} = \frac{1}{2} N x \left[\frac{d(C'_{sp,e} + C'_{rs})}{dz} \right] V_s^2$

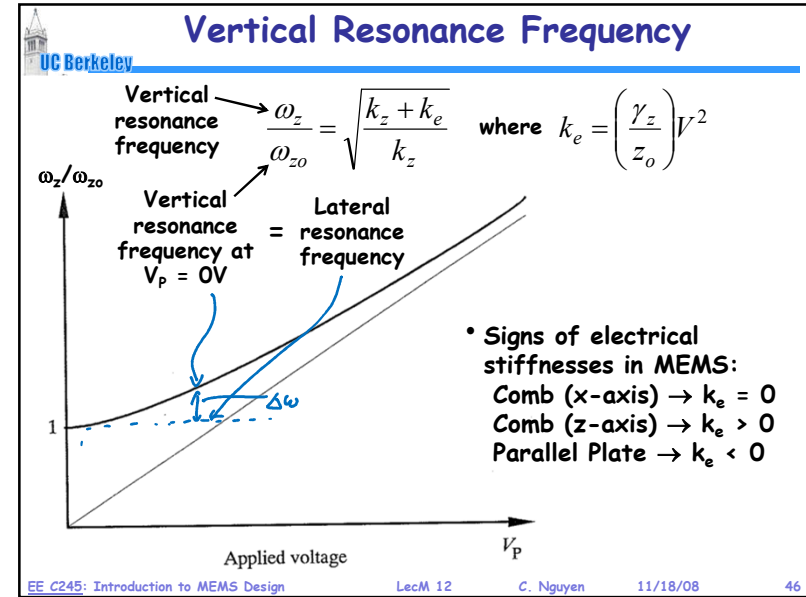
[Gary Fedder, Ph.D., UC Berkeley, 1994]

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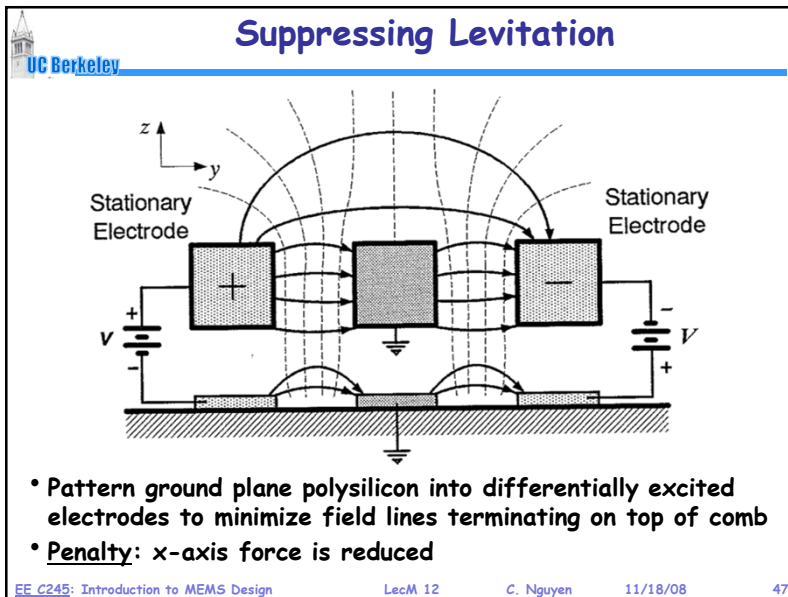
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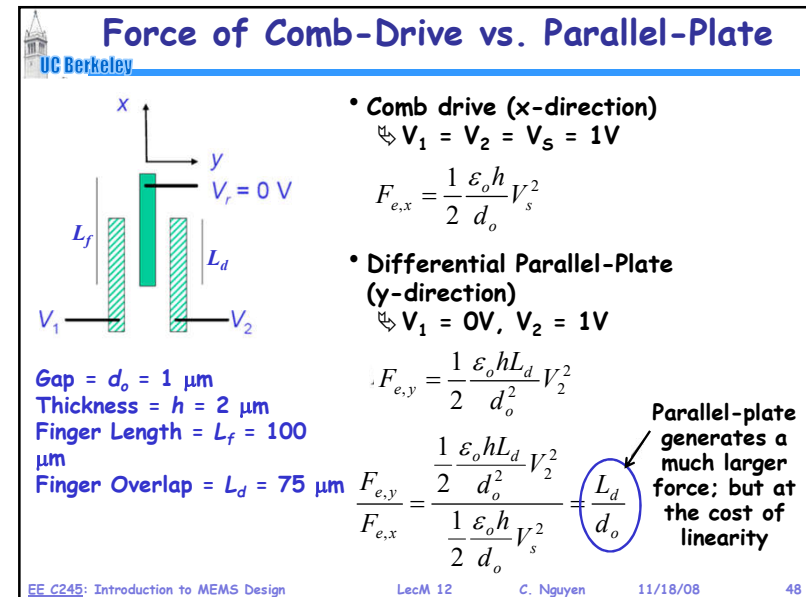
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